

The PM300 probe system is the ideal solution for engineering tests of 300 mm wafers and substrates. Whatever your application, the versatility of the PM300 meets all requirements from failure analysis (FA) to device and wafer characterization (DWC) to wafer-level reliability (WLR) testing and always ensures the highest accuracy. With the optional square chuck, the PM300 can be also used for testing of flat panel displays.

The superior mechanics of the probe system are the basis for stable and precise system setup regardless of your application. The X and Y axes of the chuck stage can be moved easily and individually for fast coarse adjustment. Each axis has been designed with an individual magnetic lock and a vacuum brake that enables the fine glide chuck stage to be exactly positioned whenever you release the button. Fine adjustment is ensured for X and Y by high-precision micrometers.

The PM300 has been designed with the user in mind. You can start out with the basic setup of the PM300 and the system is scalable to meet your expanding test requirements. For example, light-sensitive measurements in a ShieldEnclosure™, thermal chucks or various high-frequency test setups up to mmW are available. Further flexibility is achievable with motorized probe positioners.

FEATURES / BENEFITS

Flexibility	Flexible design for engineering tests Easy changeover between different applications		
	Wide range of accessories available, for example ShieldEnclosure SE1200		
	Thermal chucks (only hot) and motorized microscope available		
Stability	Superior mechanics for highest degree of stability		
Ease of use	Quick and easy system set up		
	Independent, coarse movement of X and Y axes		
	Easy fine adjustments through high-precision micrometers located on frontside of chuck stage		
	Independent magnetic locks and vacuum brakes for X and Y axes		
	Ergonomic low-profile design		



Chuck Stage

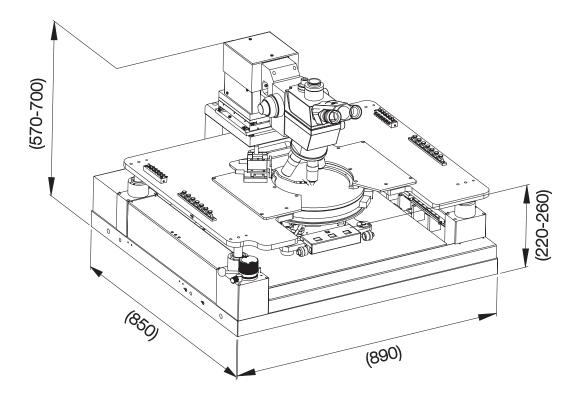
	Range of movement	X, Y, theta
	Coarse adjustment	300 mm x 300 mm
	Fine adjustment	10 mm x 10 mm (63.5 tpi)
	Planarity of granite slab	
	over entire range of movement	< ± 2.5 μm
	Load stroke	10 mm
	Theta travel	±8°
Chuck		
	Diameter	300 mm (optional square)
	Planarity	8 µm
Probe F	Platen	
	Z travel	40 mm
	Contact / Separation stroke	0.4 mm
	Utilities	
	Power	115 / 230 V, 50 / 60 Hz
	Vacuum	- 0.8 bar
	Compressed air	6 to 10 bar

^{*}Data, design and specification depend on individual process conditions and can vary according to equipment configurations. Not all specifications may be valid simultaneously.

PHYSICAL DIMENSIONS

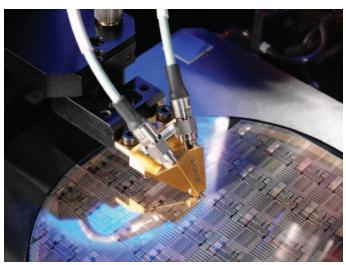
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Weight	270 kg (depending on number of accessories)
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Dimensions (mm)





PM300 with square chuck for failure analysis of FPDs.



RF setup with Dual |Z| Probe® on PM300.



PM300 with laser cutter and 300 mm x 300 mm microscope movement.

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Data subject to change without notice

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